

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Davis et al.

Serial No.:

10/628,001

Filed:

July 25, 2003

Confirmation No.: 3943

For: Method For Automatic

Determination Of Semiconductor Plasma Chamber Matching And

Source Of Fault By Comprehensive Plasma

Monitoring

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Group Art Unit: 2812

Examiner:

Unknown

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING

37 CFR 1.8

I hereby certify that this correspondence is being deposited on July 20, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

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Signature

PRELIMINARY AMENDMENT

The commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/7938/ETCH/SILICON/LYC, the fee of \$852 for 3 new independent claims and Prior to examination, please amend the above-identified 33 new total claims. application as follows:

Amendments to the Specification begin on page 2 of this paper. Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper. Remarks begin on page 14 of this paper.